

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Patent Application of:
Philippe Cormont et al.

Application No.: 10/570,726

Filed: March 6, 2006

For: Method and Device for Lithography by Extreme
Ultraviolet Radiation

Confirmation No.: 7225

Art Unit: 2851

Examiner: Steven H. Whitesell
Gordon

RESPONSE TO OFFICE ACTION DATED AUGUST 5, 2008

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

This paper is submitted in response to the non-final Office action dated August 5, 2008.

Please amend the application as follows:

Amendments to the Claims are reflected in the listing of claims which begins on page 2 of this paper.

Remarks/Arguments begin on page 10 of this paper.